



Docket No.: 2328-023RI

14/18  
*[Signature]*  
PATENT  
9/20/02

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of :  
Duane Charles GATES :  
Serial No. 09/534,814 : Group Art Unit: 3742  
Filed: March 22, 2000 : Examiner: M. Paschall  
For: SEGMENTED COIL FOR GENERATING PLASMA IN PLASMA PROCESSING EQUIPMENT

RESPONSE

Honorable Commissioner of  
Patents and Trademarks  
Washington, DC 20231

Sir:

In response to the May 21, 2002, Office Action, please amend the referenced application as follows:

IN THE CLAIMS:

Please amend claims 39, 45, 51 and 54 as follows:

39. (Amended) A low pressure plasma processor for treating a workpiece with a plasma comprising a low pressure chamber where the workpiece is adapted to be located, the chamber having an inlet for introducing into the chamber a gas which can be converted into the plasma for treating the workpiece, a coil positioned to couple an RF field to the gas for exciting the gas to the plasma state, the coil including interior, intermediate and peripheral portions, the interior, intermediate and peripheral portions having turns connected to each other and

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